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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Michael Shu-Huan Wang, et al. Docket No: TI-34402  
Serial No: 10/718,921 Conf. No: 2399  
Examiner: Shantese L. McDonald Art Unit: 3723  
Filed: 11/21/2003  
For: CHEMICAL MECHANICAL POLISHING APPARATUS AND METHOD TO MINIMIZE SLURRY ACCUMULATION AND SCRATCH EXCURSIONS

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)  
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 4-8-05.

  
Ann Trent

Dear Sir:

Responsive to the Office Action mailed January 12, 2005, in connection with the above identified application, Applicants respectfully submit the following amendments and remarks.